

# REPLACEMENT SHEET

Method and Apparatus for Low Energy Electron Enhanced Etching of  
Substrates in an AC or DC Plasma Environment      Inventors: Martin, et al.  
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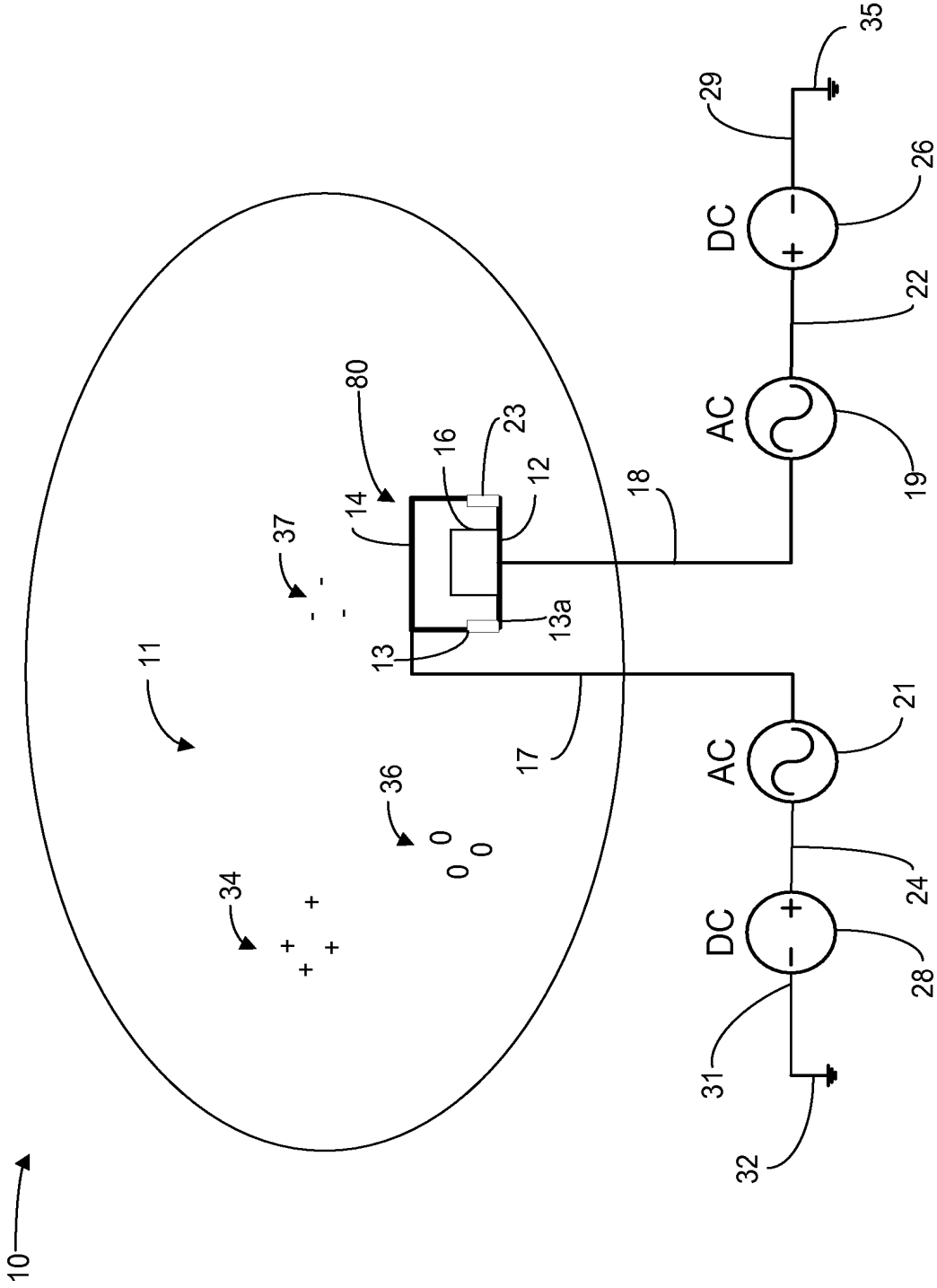


Fig. 1

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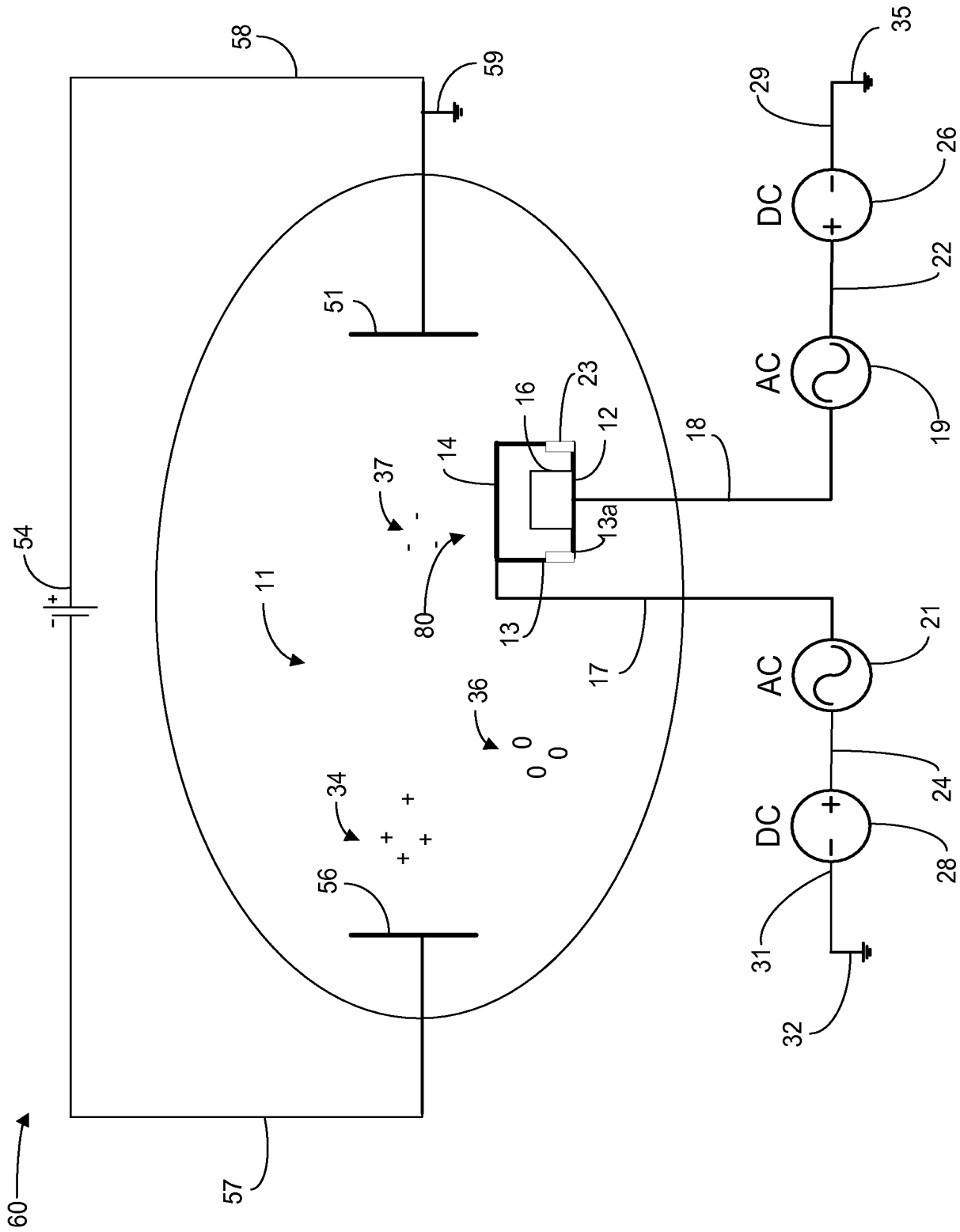


Fig. 3

Fig. 4

